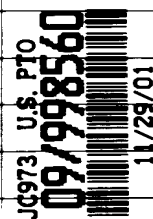


Form PTO 1449 Rev 7-80	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No Mo6644 LeA 34.976	Serial No To Be Assigned
LIST OF PRIOR ART CITED BY APPLICANT (Use Several Sheets If Necessary)		Applicant Kristina Vogt et al	Filing Date Herewith
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U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA					
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							Yes	No*
	AL	00/00567	01/06/2000	World Patent				
	AM	00/24842	05/04/2000	World Patent				
	AN	99/64527	12/16/99	World Patent				
	AO	99/47618	09/23/99	World Patent				
	AP	99/67056	12/29/99	World Patent				

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AR	Microchip Frabrication: A Practical Guide to Semiconductor Processing, Peter Van Zant ed., McGraw-Hill (month unavailable) 2000, pages 302-309 & 401-403
AS	Copper CMP: A Quistion of Tradeoffs, Peter Singer, Semiconductor International, Verlag Cahner, May 2000, pages 73-84
AT	Chemical Mechanical Planarization of Microelectronic Material, J.M. Steigerwald, S.P. Murarka & R.J. Gutmann, John Wiley & Sons, Inc. (month unavailable) 1997, CMP Variable and Manipulations, pages 42-43

EXAMINER	DATE CONSIDERED
EXAMINER Initial if referenced considered, whether or not citation is in conformance with MPEP 609: Draw line through if not in conformance and not considered. Include copy of this form with next communication to applicant.	

* Neither English Language Equivalent nor an English Language Translation is available.